

**Amendment to the Specification:**

***Please amend the paragraph bridging pages 3-4 as follows:***

-- The switch 112 is preferably a movable MEMS switch. The microphone system 100 realizes dual microphone behavior by incorporating the movable MEMS switch 112 that closes or opens the directional port 110 thus making the microphone 102 have omni or directional behavior respectively. The directional port 110 is therefore a selectable directional port that can be enabled by closing the switch 112 and disabled by opening the switch 112. The movable MEMS switch 112 can easily be manufactured along with the microphone diaphragm ~~408~~ 114 and other electrically active elements using the same, related or complementary MEMS process. Movable MEMS switch 112 can be formed of a variety of MEMS elements such as cantilever beams, torsional beams, sliding disks, and other MEMS elements which are well known in the art. The movable MEMS switch 112 can be controlled by a variety of means known in the art including but not limited to electrostatic, capacitive, magnetic or piezoelectric means. --

***Please amend the first full paragraph page 6, lines 3-9, to read as follows:***

-- FIG. 3 shows a microphone system 300 formed in accordance with another embodiment of the invention. The microphone system 300 includes a MEMS microphone 302 having a front volume portion 304 and a rear volume portion 306 on either side of a diaphragm 314, an audio port 308 accessing the front volume portion 304, a plurality of audio ports 310, 320 for accessing the rear volume portion 306 of the microphone for directionality, acoustic flow resistive material 316 coupled to at least one of the audio ports 310, 320 and at least one switch 312 for sealing and unsealing the plurality of audio ports 310. --